

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Appln. Of: ANDRE et al.

Serial No.:

10/067,912

Filed:

June 27, 2003

For:

THIN LAYER OF HAFIUM OXIDE AND DEPOSIT PROCESS

Group:

1762

Confirmation No. 8153

Examiner:

Markham, Wesley D.

DOCKET: BREV 13186 DIV

MAIL STOP ISSUE FEE Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

TRANSMITTAL LETTER

Dear Sir:

The Notice of Allowance mailed March 20, 2006 is at hand. Applicants note that the Examiner did not initial and date the PTO-892 filed with the Information Disclosure Statement mailed June 27, 2003. An additional copy of the Information Disclosure Statement is enclosed for the convenience of the Patent Office.

> Respectfully submitted, Noman Nolmay

Norman P. Soloway Attorney for Applicants

Reg. No. 24,315

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail in an envelope addressed to: MAIL STOP ISSUE FEE, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on

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MAIL STOP PATENT APPLICATION Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

Dear Sir:

The present application is a divisional of U.S. Patent Application Serial No. 09/830,380, filed April 25, 2001. Applicant hereby attaches copies of Form PTO-1449 and Form PTO 892 from the parent application. Copies of the various prior art references listed in the attached Forms PTO-1449 and PTO-892 are not being furnished, since they are available in the parent application. Accordingly, it is respectfully submitted that no copies of these references are believed necessary. The claims in the present application are believed to be patentably distinguished over these references.

This information disclosure statement is being made pursuant to the duty of disclosure imposed by law and formulated in 37 CFR 1.56(A). No representation is made that the information thus disclosed in fact constitutes prior art or that it is the closest prior art, inasmuch as 37 CFR 1.56(A) relies on a materiality concept which depends on subjectivity.

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Docket: BREV 13186 DIV Information Disclosure Statement

In the event there are any fee deficiencies or additional fees are payable, please charge them (or credit any overpayment) to our Deposit Account No. 08-1391.

Respectfully submitted,

Norman P. Soloway Attorney for Applicant

Reg. No. 24,315

CERTIFICATE OF EXPRESS MAILING

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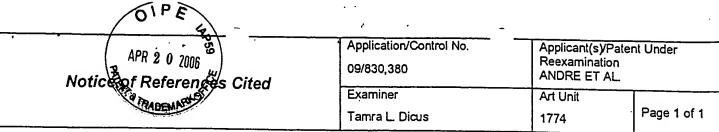
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U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name .	Classification
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FOREIGN PATENT DOCUMENTS

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NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).) Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.

EXAMINER DATE CONSIDERED

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

		Docket Number (Optional)	Application Number					
INF	ORMATION DISCLOSURE CITATION	Applicant(s)						
	(Use several sheets if necessary)	ANDRE et al						
	(^ oq 2 0 2006 m)	Filing Date APRIL 25, 2001	Group Art Unit					
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	, pg. 513-525							
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